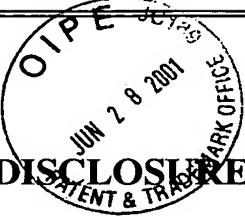
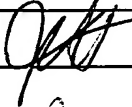
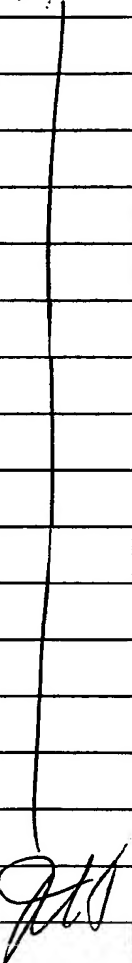
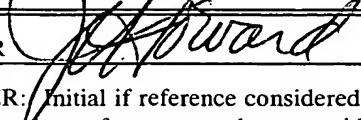
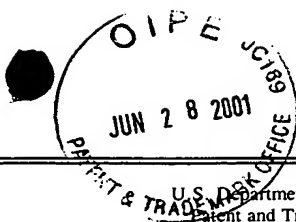


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<b>INFORMATION DISCLOSURE STATEMENT</b> (Use several sheets if necessary)				Applicant MCNALLAN, ET AL.		
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U.S. PATENT DOCUMENTS							
*Examiner Initials		Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate
 	A1	3,949,106	04/06/76	Araki et al.	427	249	
	A2	3,977,896	08/31/76	Bokros et al.	427	213	
	A3	4,016,304	04/05/77	Beatty et al.	427	6	
	A4	4,173,522	11/06/79	Pulker et al.	204	192 C	
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	A6	4,569,738	02/11/86	Kieser et al.	204	173	
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*Examiner Initials		Document Number	Publication Date	Country	Class	Subclass	Translation	
							Yes	No
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	B2	07232978	1995.09.05	Japan				
	B3	60067651A	1985.04.18	Japan			Abstract	
	B4	63018077A	1988.01.25	Japan			Abstract	
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	C1 Gogotsi, et al., "Formation Of Carbon Coatings On SiC Fibers By Selective Etching In Halogens And Supercritical Water", <i>Ceram. Eng. Sci.</i> , Vol 19, No. 3, (1998), pp. 87-94 (Note: This issue of <i>Ceramic Engineering and Science Proceedings</i> contains the papers presented at the 22 <sup>nd</sup> Annual Conference on Composites, Advanced Ceramics, Materials, and Structures, held at Cocoa Beach, Florida in January, 1998)

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	C4	McNallan, et al., "Preparation Of Carbon Films By High Temperature Chlorination Of Metal Carbides", <i>Proceedings, Ninth International Conference on High Temperature Materials Chemistry</i> , PV 97-39, K.E. Spear, Ed., The Electrochemical Society, Inc., Pennington, NJ, 1997, pp. 529-536
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